

AMENDMENTS TO THE CLAIMS

Claims 1-14 (Cancelled).

15. **(Currently Amended)** A composite processing method comprising:

separately providing a mechanical processing section for processing a surface of a substrate by ~~a processing method involving~~ a mechanical action, and an electrolytic processing section, having a processing electrode provided with an ion exchanger, for processing the substrate by applying a voltage between the processing electrode and the substrate while keeping the ion exchanger in contact with the substrate; and

carrying out processing of the surface of the substrate with the mechanical and electrolytic processing sections by moving the substrate and the mechanical processing section relative to each other and moving the substrate and the processing electrode relative to each other, while keeping the ion exchanger and the mechanical processing section in contact with the substrate such that the electrolytic processing section electrolytically processes the surface and the mechanical processing section removes a passive film formed during processing with the electrolytic processing section; and

re-processing the surface with the electrolytic processing section after said processing of the surface with the mechanical and electrolytic processing sections.

Claims 16-28 (Cancelled).

29. **(Currently Amended)** A composite processing method comprising:

providing a fixed-abrasive processing section for processing a surface of a workpiece by ~~a processing method involving~~ a mechanical action ~~by involving~~ a fixed abrasive containing abrasive grains, and an electrolytic processing section, having a processing electrode and a feeding electrode, for processing the workpiece by applying a voltage between the processing electrode and the feeding electrode; and

carrying out processing of a the surface of a the workpiece with the fixed-abrasive processing section by moving the workpiece and the fixed-abrasive processing section relative to each other, other while keeping the fixed abrasive in contact with the workpiece so as to form a plurality of fine, removable scratches in an entirety of the surface; and

processing the surface of the workpiece with the electrolytic processing section by moving the workpiece and the electrolytic processing section relative to each other while applying a voltage between the processing electrode and the feeding electrode so as to remove the plurality of fine, removable scratches to obtain a flattened processed surface.

30. **(Currently Amended)** The composite processing method according to claim 29, wherein after said processing of the surface of the workpiece with the fixed-abrasive processing section ~~by bringing it into contact with the workpiece~~, the workpiece is processed only with the electrolytic processing section.

Claims 31 and 32 (Cancelled).

33. **(New)** The composite processing method according to claim 29, wherein in said processing of the surface with the fixed-abrasive processing section, the plurality of fine, removable scratches are formed so as to have a depth of less than or equal to $0.5\mu\text{m}$.